

DESCRIPTION

~~WORKPIECE-HOLDING-DEVICE~~

TECHNICAL FIELD

[0001]

The present invention relates to an apparatus for holding a workpiece when transporting a workpiece such as a silicon wafer.

BACKGROUND ART

[0002]

For in-process transportation of a wafer in a processing step of a thin plate-form workpiece such as a silicon wafer, for example, it is usual to use a box or a cassette having plural of slots to store one wafer per each. The transported box or cassette is set to a processing apparatus in a step at the destination, and the wafers are taken out therefrom and are set to the processing apparatus. The wafers subjected to the processing are stored to a box or a cassette again, and transported to the next step.

[0003]

On this occasion, the transportation of wafers, in which wafers are taken out from a box or a cassette, set to a processing apparatus, and stored to a box or a cassette, are performed automatically by a robot or an actuator, etc. without handwork in many cases.

In such transportation of wafers, wafers are held by a hand attached to a robot or an actuator (hereinafter, also referred to as a workpiece holding apparatus), transported to the destination, and released thereto (see Patent Document 1). In this case, it is

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